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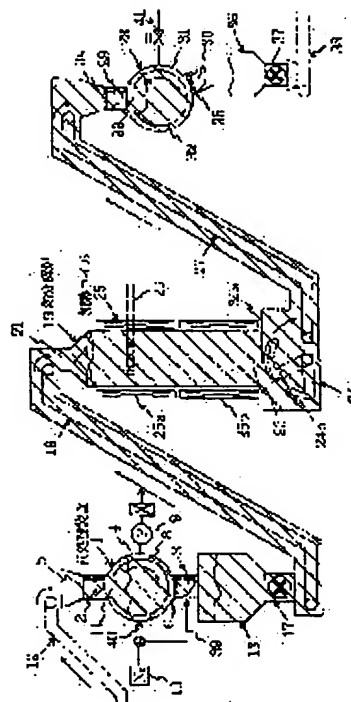
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(54) ORGANIC COMPOUND DECOMPOSING AND TREATING DEVICE

(57)Abstract:

PROBLEM TO BE SOLVED: To improve a thermally decomposing quality and thermal efficiency in an organic compound decomposing and treating device where an organic compound component in a waste is removed by a thermal decomposition.

SOLUTION: The organic compound decomposing and treating device comprises a pretreatment device 1 for vacuum drying a substance to be treated and a thermal decomposition furnace 19 for heating the substance to be treated in an atmosphere where oxygen is blocked and decomposing and treating the organic compound component of the substance to be treated, and the substance to be treated is vacuum sucked prior to the thermal decomposition of the substance to be treated. This vacuum sucking allows the inside of the substance to be treated to be completely deaerated, oxygen blocking in the thermal decomposition furnace 19 to be definitely performed and a solution (water content) to be completely vacuum dried, thereby eliminating the loss of a heating energy due to the vaporization of a remaining solution. In addition, the system can dispense with a separate feeding mechanism and the structure of the thermal decomposition furnace can be simplified by allowing the thermal decomposition furnace 19 to be of a hollow cylindrical vertical type and by allowing the substance to be treated to be moved inside the furnace due to a drop generated by the own weight of the substance.



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